### Test procedures for ALICE Silicon Pixel Detector ladders

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## Large Hadron Collider

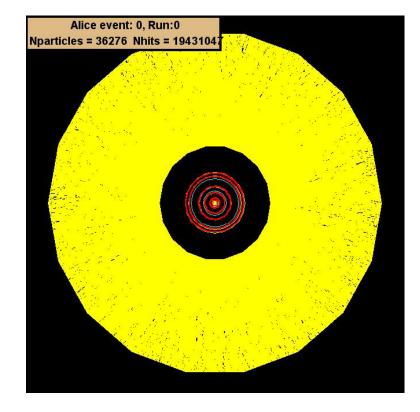


### Some numbers related to ALICE and LHC

#### □ 5.5 A TeV Pb-Pb

#### $\Box$ Expected multiplicity $(dN_{ch}/dy)_{y=0}$ :

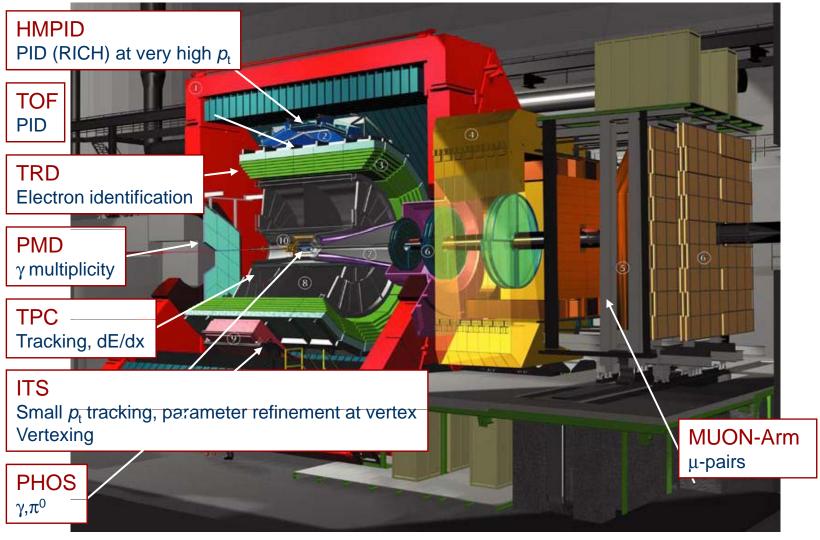
- > Major uncertainties not completely resolved
- > Still no safe way to extrapolate
- > Simple scaling form RHIC  $\rightarrow$  ~2500
- > Safe guess → ~1500 6000
- > Worst case  $\rightarrow$  ~8000
  - Baseline in the project
- □ Luminosity for Pb-Pb:
  - >  $\mathcal{L}_{max} = 1 \times 10^{27} \text{ cm}^{-2} \text{s}^{-1}$



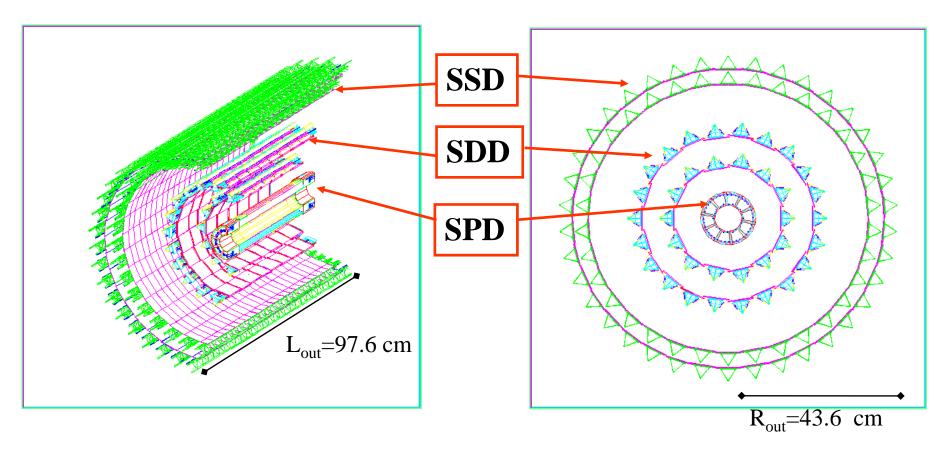
...and the worst case for

# ALICE

#### The ALICE detector



# Inner Tracking System (ITS)



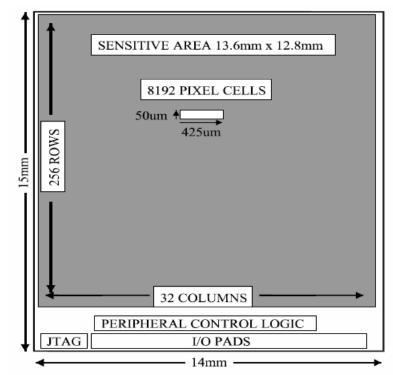
- □ 6 Layer, 3 technologies (occupancy ~2% at max multiplicity)
  - Silicon Pixels (0.2 m<sup>2</sup>, 9.8 Mchannels. Single chip size = 50x425 µm)
  - > Silicon Drift (1.3 m<sup>2</sup>, 133 kchannels)
  - > Double-sided Strip (4.9 m<sup>2</sup>, 2.6 Mchannels)

# **ITS performances**

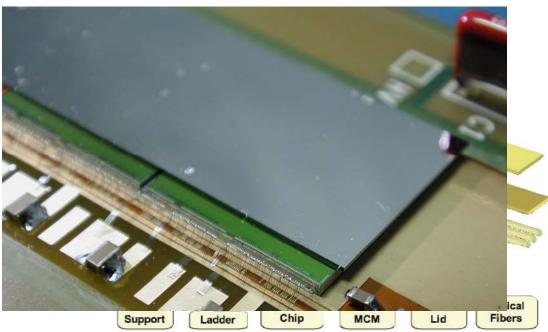
	Layer 1, 2 Pixel (SPD)	Layer 3, 4 Drift (SDD)	Layer 5, 6 Strip (SSD)
Δ(rφ) (μm)	12	38	20
Δ <b>z (μm)</b>	100	28	830
Two track resolution rφ (μm)	100	200	300
Two track resolution z (µm)	850	600	2400
Cell size (µm <sup>2</sup> )	50 × 425	150 × 300	95 × 40000
X/X <sub>o</sub> (1%)	2.0	2.2	<b>1.76</b> <sup>6</sup>

### Silicon Pixel Detectors

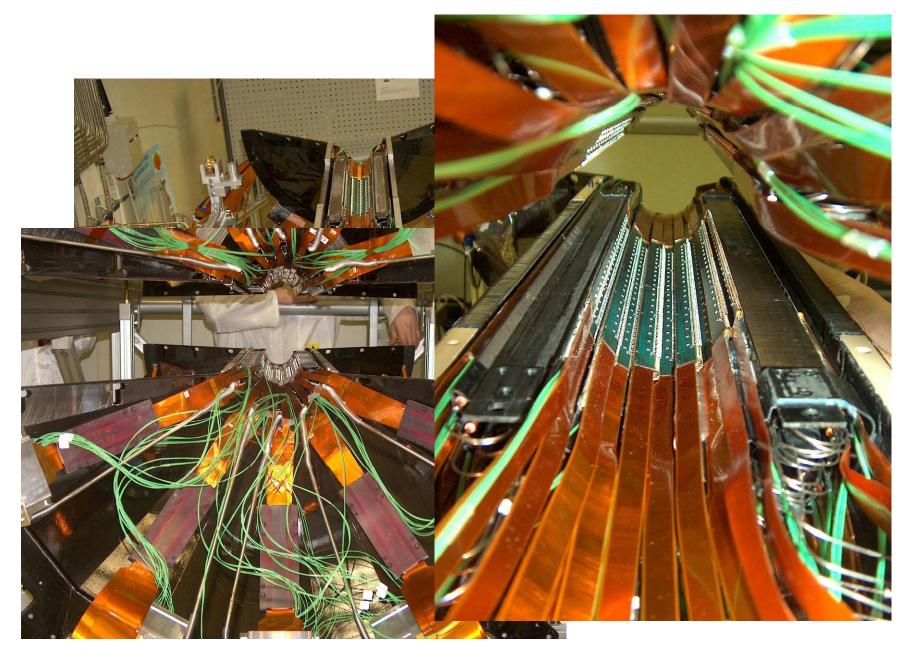
- □ ASIC Chip (150 µm thick):
  - > 8192 pixels (256 columns \* 32 rows)
  - > sensitive area: 13.6 mm x 12.8 mm
- □ Silicon sensor (200 µm thick)
  - > size: 70.7 mm x 16.8 mm
- □ Elementary assembly: the "Ladder"
  - > = 1 Si sensor bump-bonded to 5 chip cells





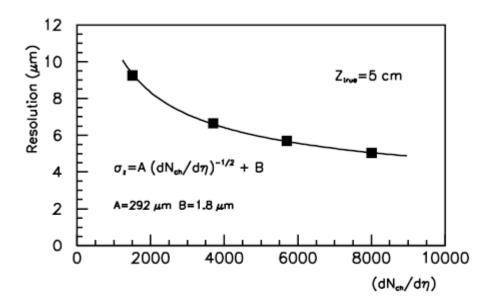


#### Silicon Pixel Detectors



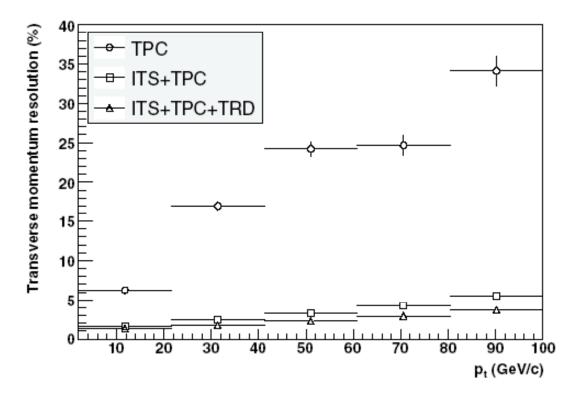
# ITS purposes

- Track propagation to the closest distance from the interaction point
  - > Best resolution for all track parameters
- Tracking of low transverse momentum particles



#### Main SPD contributions:

- Primary vertex estimation before tracking (and used as a constraint for primary particles tracking)
- Event multiplicity evaluation
- Secondary vertices detection
  - > D, B
  - > strangeness



### SPD test: work sequence

□ Step 1: wa chips are > each chir > chips wh > □ Step 2: la ladders a > and also when at > (bad chip



> when too many chips are not good, the ladder is rejected

#### SPD test: evaluation criteria

#### □ Chips:

- > Class I "good"
  - used to build ladders
- > Class II "not too bad"
  - used for tests
- > Class III "bad"
  - rejected

#### □ Ladders:

- > Class I: "good"
  - used to mount half-staves
  - When: all class I chips
- > Class II: "not too bad"
  - reworked to be re-tested
  - used for test
  - When: at least one class 2 chip
- > Class III: "bad"
  - if just 1 bad chip  $\rightarrow$  rework
  - If too many bad chips  $\rightarrow$  reject
  - When: at least one class 3 chip

## Chip test sequence (I)

#### □ Test of currents in the chip:

- > too high values can damage the chip (or the testing apparatus) or cause the chip not to work properly
- > Test protocol: threshold values for maximum allowed currents
  - If I\_analog > max or I\_digital > max → CLASS 3

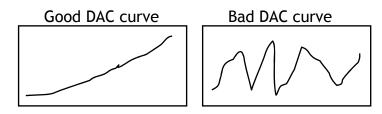
#### □ Test of JTAG:

- > JTAG is fundamental for the dialog between the chip and the computer which must control it and read data from it
  - *if JTAG test fails* → *CLASS* 3

### Chip test sequence (II)

□ Test of digital-to-analog converters (DAC)

- > DAC are fundamentals both for setting working parameters of chips and to read signals from them
- > Requirement: the conversion DAC curve must be smooth
  - if at least one DAC curve is not smooth → CLASS 3



#### □ Minimum threshold search:

- > Requirement: a value must be found for which NO pixels fire due to electronic noise only
  - if at least one pixel cannot be switched off (by lowering the threshold or masking that pixel), and then no minimum threshold is found → CLASS 3

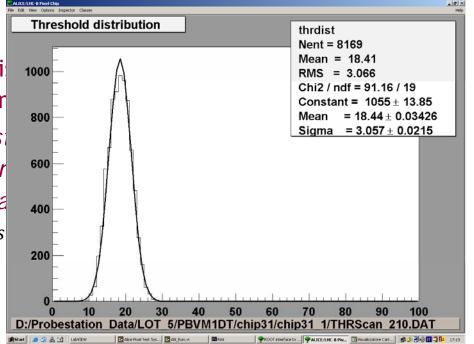
### Chip test sequence (III)

#### Pixel matrix test

- > for 100 times, a MIP-like signal is sent to each pixel, when the whole chip is set to the minimum threshold value found before
- Requirement: all pixels must respond to this signal almost always (~100 times).
  - if more than 1% (=82) pixel are underefficient or overefficient → CLASS 2

#### □ Threshold scan:

- > a signal is sent to the chip, which i (60mV) to zero: at each step, the r
- Requirement: responding pixel dist must have a mean value not larger waferprobing step, 60 mV in the la
  - if the mean of threshold distribution is



## Chip test sequence (IV)

□ Fast-OR minimum threshold

- > Fast-OR signal is generated by the chip when at least one chip responds.
- > It can be used as a trigger during data acquisition.
- > Requirement: a threshold value must be found for which the pixel does not return a FO signal in absence of signal (i.e. due to noise)
  - if no FO minimum threshold is found → CLASS 3

# *Average required time for a complete chip test: 10 min.*

#### Detector test sequence

#### □ Leakage current

- > Requirement: not larger than a threshold value (1 mA) when applying standard bias
  - if leakage current is too large → CLASS 2

#### □ Detector response:

- > the detector is exposed to a 37 MBq <sup>90</sup>Sr source
- > Requirement: 1% maximum pixel defects (dead or noisy)
  - if there are > 1% dead/noisy pixels or entire dead/noisy columns → CLASS 2
  - if there is are too many dead/noisy pixels or dead/noisy zones in the matrix → CLASS 3

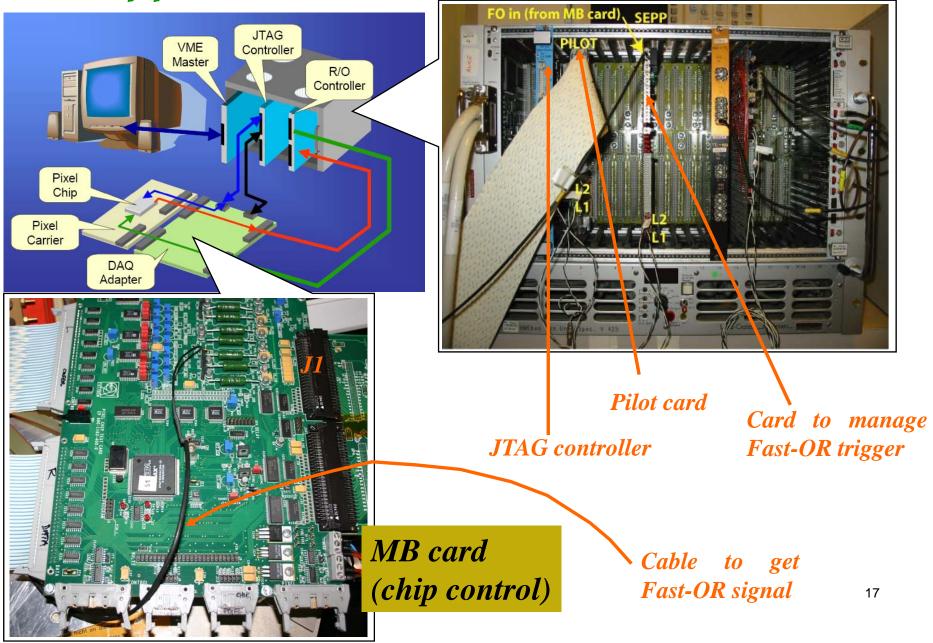
#### □ Visual inspection of the detector surface:

- required to detect surface defects, holes, deep scratches which could cause the detector not to work properly
  - if defects are absent/negligible → CLASS 1
  - If defects are serious (deep holes or scratches) → CLASS 3 not reworkable

# Average time requirement for a complete ladder test: 3.5 hours

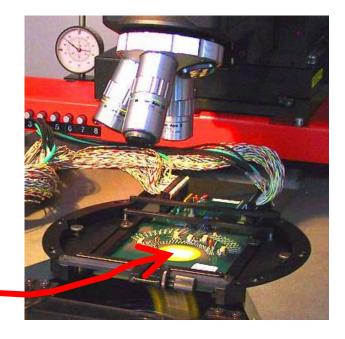
#### Test apparatus

#### VME Crate



#### **Probe station**

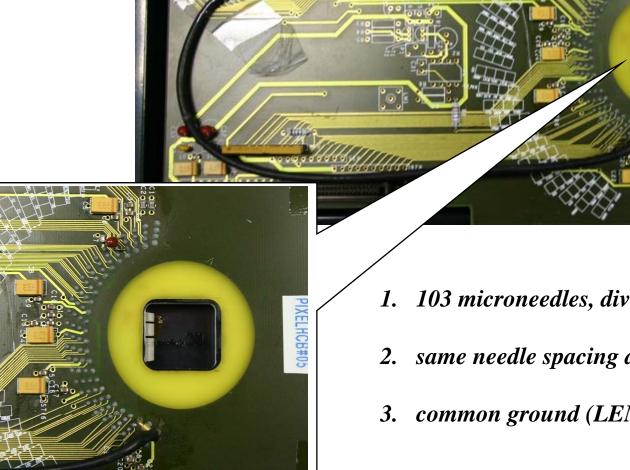
- □ Suppor for tested device
  - > "chuck"
- Probe card with needles which create the contact with the tested chip





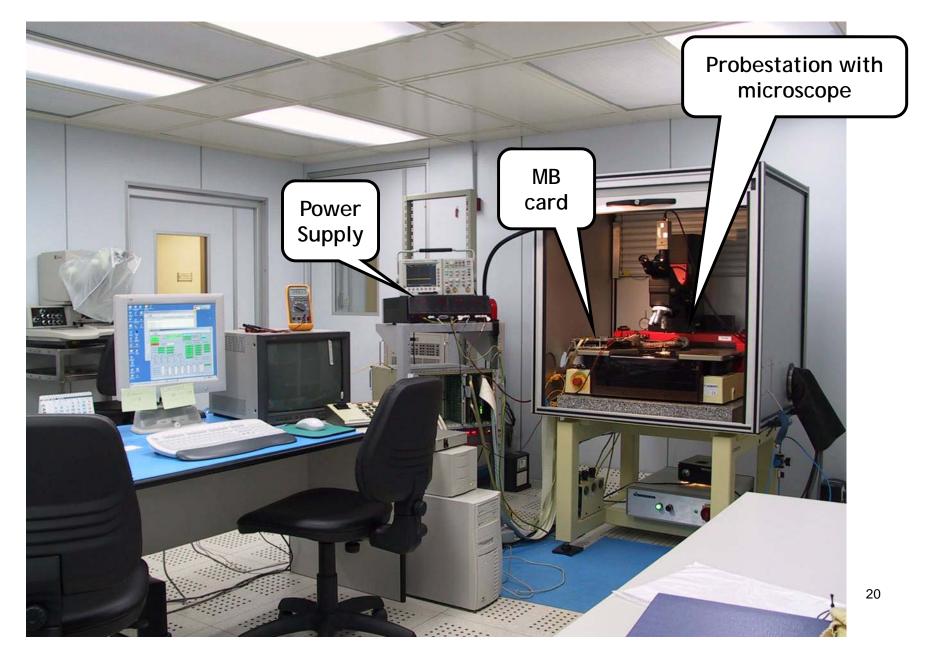
trace left by previous contact (re-testing)

### **Probe card**

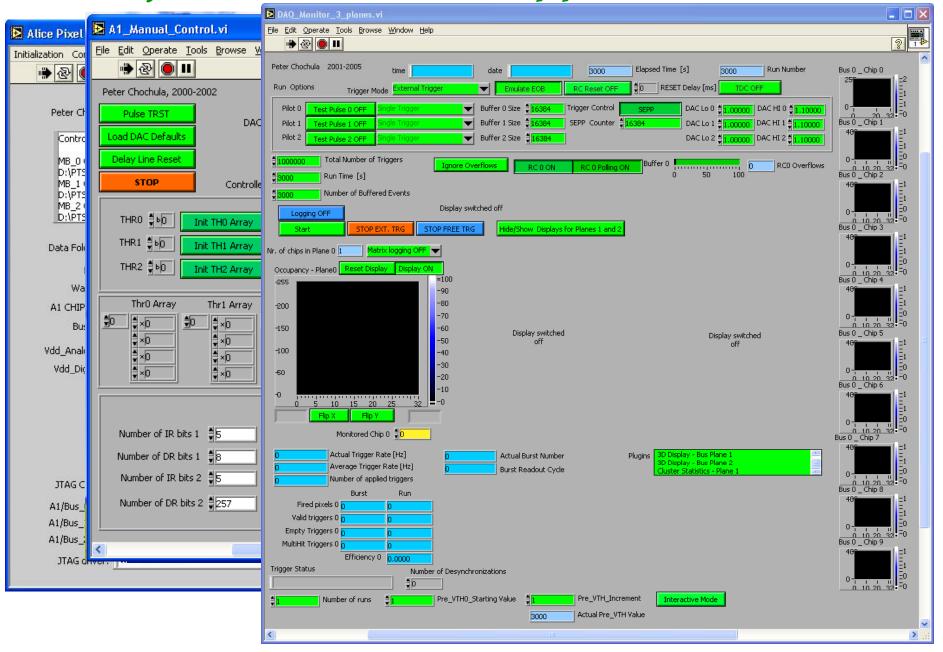


- 1. 103 microneedles, divided in 3 groups
- 2. same needle spacing as chip pads one
- 3. common ground (LEMO cable)

#### Clean room in Catania



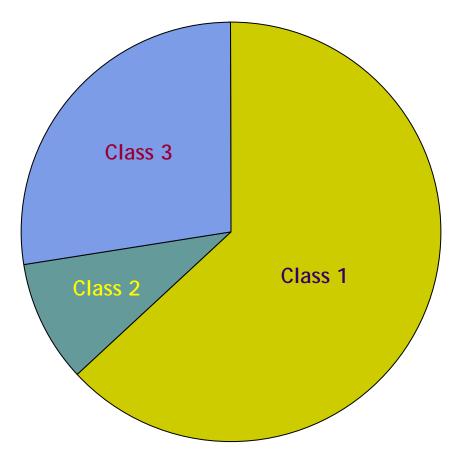
#### Test software: LabView application



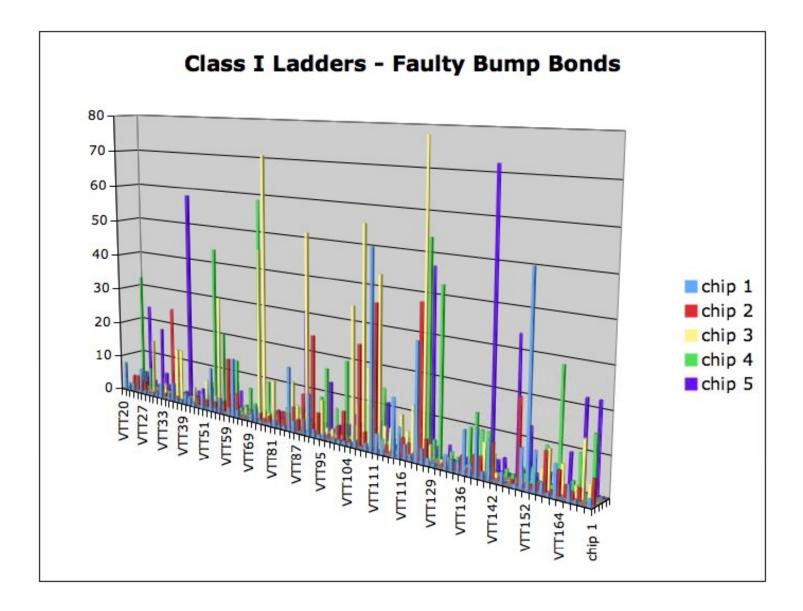
# Ladder tests in Catania: summary from November 2005 up to now

#### □ 240 ladders tested:

- > 151 (= 62.9%) class 1
- > 23 (= 9.6%) class 2



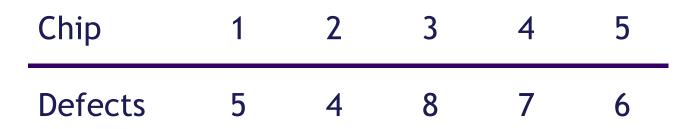
#### **Statistics**

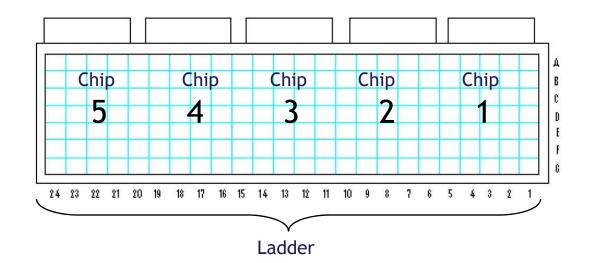


#### **Statistics**

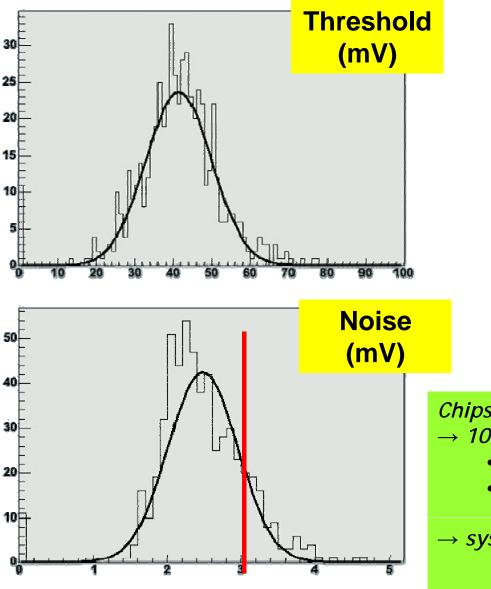
Average number of defects per chip position:

**Class I ladders** 





#### Average min. threshold & noise



□ Avg. Threshold: > 41.1 ± 0.5 mV ~ 2400 e-□ Avg. Noise: > 2.45 ± 0.03 mV ~140 e-□ Good *S*/*N* ratio □ Efficiency ~1 at experimental phase

Chips with avg. noise > 2.8 mV

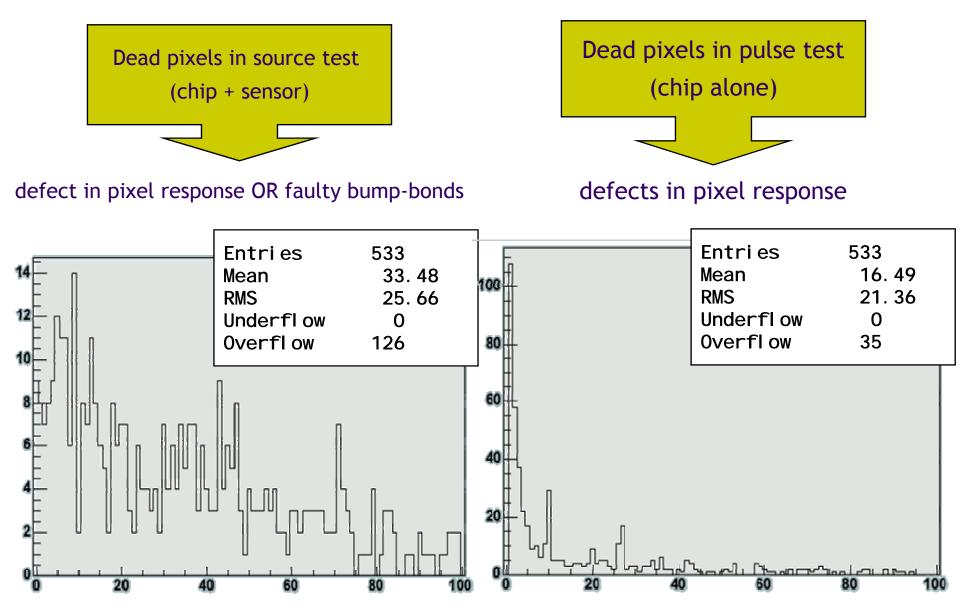
- → 100 readout chips
  - 82 from production lots #7 and #8
  - avg. Noise = 3.15 ± 0.03 mV

→ systematic effect due to production process

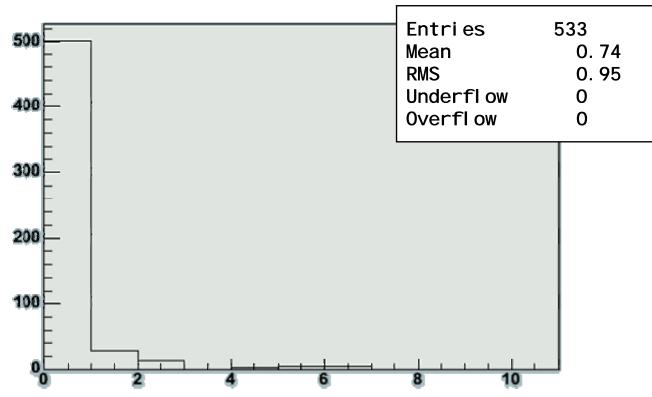
(source: Carmelo Digiglio – INFN Bari)

# **Dead pixels**

A pixel is "dead" when it does not respond to impulses given by pulse or source



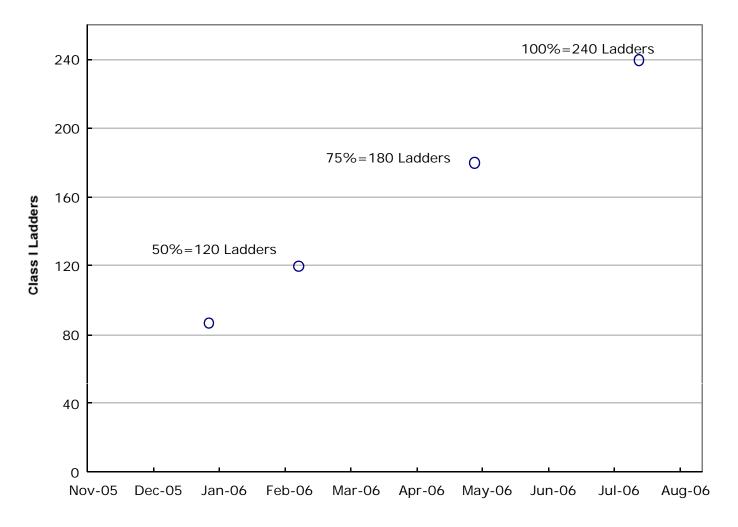




10<sup>6</sup> trigger signals sent during test phase noisy pixels  $\rightarrow$  #hits > 10<sup>4</sup> (1% of #triggers) 94% sample  $\rightarrow$  1 noisy pixel = 0.1‰ of total Max number of noisy pixels in a single chip = 7 (0.08% of the total)

#### Ladder production

#### **Class I Ladders Production**



### Summary

- □ SPD is a fundamental module for several purposes in ALICE event reconstruction.
- Building SPD requires an accurate testing procedure of each of its single components (ladders/chips), and for several aspects:
  - > performances
  - > defects
  - > working parameters
  - > PC to device communication
- Catania's group has given a large contribution to this testing activity, since 2004 up to the end of production required for SPD commissioning (first half of 2007).
- □ Future plans:
  - > tests for spare modules
  - $\rightarrow$  looking forward to start using them with LHC beam!  $\textcircled{\odot}$
- □ Thanks to Carmelo Digildo for contributions to the statistics plots

